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(54) METHOD FOR EVALUATING SEMICONDUCTOR WAFER

(57)Abstract:

PROBLEM TO BE SOLVED: To provide a technique capable of evaluating kinds of defects (actual defects) present in a semiconductor wafer in a short time and by a simple method.

SOLUTION: In a method for evaluating a semiconductor wafer, a relation of aspects of defects of the semiconductor wafer and kinds of defects has been beforehand acquired, and based on this relation, the kind of defects is determined from the aspects of the defects of the semiconductor wafer to be evaluated.

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